

Feature

- Precision MEMS process
- High performance, shielded, Micro-cavity structure
- Silicon substrate, 50Ω CPW output
- Au wire bonding, for MCM applications

Environmental Specifications

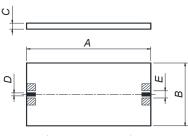
Operating Temperature	-55℃~+85℃	
Storage Temperature	-55℃~+125℃	
Max. Input Power	35dBm	

Electrical Specifications(T_A=+25°C)

Parameter	Min.	Тур.	Max.	Unit
Center Freq. (f₀)	-	5.65	-	GHz
Pass Band	5.4	-	5.9	GHz
Ripple in Pass band	-	-	1	dB
Insertion Loss @ fo	-	-	3	dB
Return Loss	10	-	-	dB
Out of band	≥30@4.8GHz&6.2GHz			dB
Attenuation	≥40@4.7GHz&6.4GHz d			dB
Group Delay Variation	≤0.7@5.4~5.9GHz ns			
Linear Phase	≤±7@5.4~5.9GHz			

S2P file name: SiMS5R6_R6-6D3.s2p

Outline Drawing



■I/O PORT 図GOLD/GROUND

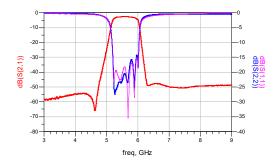
Symbol	Value (mm)			
Syllibol	Min.	Nominal	Max.	
Α	6.4	-	6.5	
В	6.4	-	6.5	

Typical Test Curves

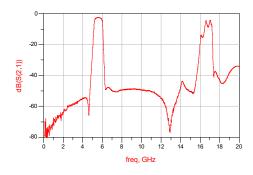
Insertion Loss VS Frequency (T_A=25°C)



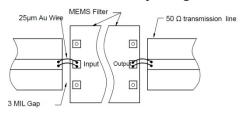
Insertion Loss & Return Loss VS Frequency (T_A=25°C)



Broadband Insertion Loss VS Frequency (T_A=25°C)

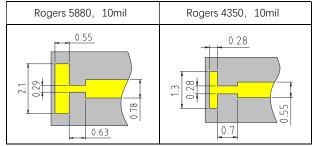


Recommended Assembly Diagrams



Application Notes:

- 1. The chip is back-metalized and can be die mounted with AuSn eutectic performs or with electrically conductive epoxy (for example ME8456).
- 2. The die should be assembled on carriers like Kovar or Mu-Cu which have same Coefficient of thermal expansion. (2.9ppm/°C) with Silicon, thickness 0.2mm max.
- 3. Handle the chips in a clean environment. DO NOT attempt to clean the chip using liquid cleaning systems.
- 5. Recommended to use T structure as below for bonding.



6. If you have any questions, please contact us.